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(71) Applicant: **MURATA MACHINERY, LTD.** [JP/JP]; 3 Minami Ochiai-cho, Kisshoin, Minami-ku, Kyoto-shi, Kyoto, 601-8326 (JP).

(71) Applicant (*for AG only*): **MURATA MACHINERY USA, INC.** [US/US]; 2120 Queen City Drive, Charlotte, 28208 (US).

(72) Inventors: **SCHOBBER, Thomas**; c/o Murata Machinery, Ltd., 136, Takeda Mukaishiro-cho, Fushimi-ku, Kyoto-shi, Kyoto, 612-8686 (JP). **RAHRBACH, Bernd**; c/o Murata Machinery, Ltd., 136, Takeda Mukaishiro-cho, Fushimi-ku, Kyoto-shi, Kyoto, 612-8686 (JP). **WOHANKA, Christian**; c/o Murata Machinery, Ltd., 136, Takeda Mukaishiro-cho, Fushimi-ku, Kyoto-shi, Kyoto, 612-8686 (JP). **FENNER, Yves**; c/o Murata Machinery, Ltd., 136, Takeda Mukaishiro-cho, Fushimi-ku, Kyoto-shi, Kyoto, 612-8686 (JP). **DOVIDS, Gerhard**; c/o Murata Machinery, Ltd., 136, Takeda Mukaishiro-cho, Fushimi-ku, Kyoto-shi, Kyoto, 612-8686 (JP). **FIDDES, John**; c/o Murata Machinery,

(54) Title: SUBSTRATE CARRIER AND SUBSTRATE CARRIER STACK

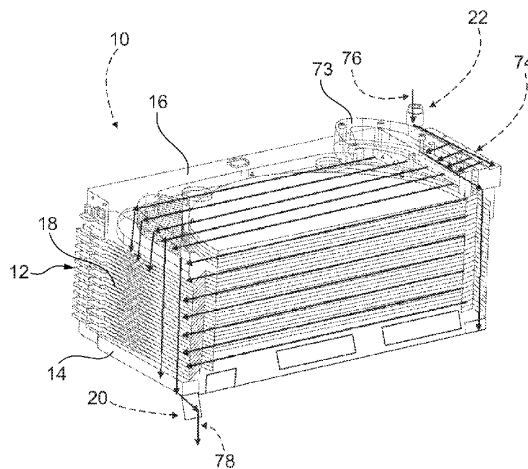


Fig. 8B

(57) Abstract: A substrate carrier stack includes substrate carriers which are stacked or stackable on each other and carry substrates within an inner accommodation space of the substrate carrier stack. The substrate carrier stack includes at least one first purging channel and at least one second purging channel, which extend vertically parallel to the inner accommodation space at opposing sides thereof, and purging structures which enable horizontal purging flows within the substrate carrier stack through spaces between substrates held by the substrate carriers. The substrate carriers each include an outer carrier frame provided with a seat to carry a substrate, wherein the outer carrier frame extends around the first and second purging channels and the inner accommodation space.

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Ltd., 136, Takeda Mukaishiro-cho, Fushimi-ku, Kyoto-shi,
Kyoto, 612-8686 (JP).

(74) **Agent: MEDLEY, Peter**, 1800 Alexander Bell Drive,
Suite 200, Reston, Virginia 20191-5465 (US).

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